

# CHLORO-SILANE DISPROPORTIONATION MODELING A MONO-CHAMBER REACTOR

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## Abstract

#### Content

This document presents an estimation of the chemical concentrations in a disproportionation reactor chamber, based on Gibbs free energy minimization. The modeling assumes thermodynamic equilibrium and mono-chamber reactor.

#### Context

This is documented as a R&D support to silane production activities. It follows a previous report on the techno-evolution of TCS disproportionation.

#### Summary

The Gibbs free energy is estimated in a mono-chamber reactor with given temperature, stoichiometry and pressure, and considering both liquid and vapour phases at a fixed ratio. This function is minimized to estimate the concentrations of the chemicals at equilibrium.

As expected from Denal data (available for a liquid phase only), the disproportionation of HSiCl3 gives  $\sim 10\%$  of H2SiCl2 in the liquid phase, and 17.7% in the vapour phase. The disproportionation of H2SiCl2 in also compatible with Denal data (18.6% H3SiCl in the liquid phase, 31.6% H3SiCl in the vapour phase), but we note some divergence for the other chemicals (to be reconsidered).

After the changing various parameters of the model we conclude that:

- Adding a liquid catalyst that is little volatile is a way to reduce the pressure, and in return pressure regulates the concentration of the catalyst.
- Disproportionation of HSiCl3 at lower temperature gives a significantly lower amount of H2SiCl2 in output.
- From a thermodynamic perspective, HCl reacts with the chlorosilanes to suppress the H-Si bounds, and evolve H2.
- An hypothetical decomposition of HSiCl3 to SiCl4, Si, HCl and H2 is found thermodynamically viable (although it may not be observed).

#### Anticipated steps:

The present mono-chamber model will be used to estimate concentrations in a multiplateau disproportionation reactor, using an iterative approach. Also, this document will be followed by a study on chlorosilane disproportionation kinetics.



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### **1. INTRODUCTION**

In the Denal plant, HSiCl3 (trichlorosilane or TCS) or H2SiCl2 (dichlorosilane or DCS) is transformed into SiH4 (silane) and SiCl4 (tetrachlorosilane). This is obtained by several reaction and distillation steps which progressively separate hydrogen-containing (volatile) species and chloride containing (non-volatile) species. The disproportionation reactions are led directly within a plateau-type distillation column. A non-volatile liquid catalyst is flown (and cycled) from top to bottom of the distillation column, so that disproportionation reactions occur in the liquid phase, on each plateau (3.5 bar).



Denal disproportionation apparatus

In a UC solid catalyst disproportionation apparatus, disproportionation reactions and separations are led in separate chambers, each reactor being at a given temperature and containing a solid bed of catalyst.

In the following, we use a model for a reactive chamber that is mono-temperature. This can be understood both as a single plateau in the Denal type reactive distilator, or as a single reactor in a UC apparatus. The present model depends only on temperature, stiochiometry, pressure, and liq to vapour molar ratio.



Some experimental and model data for such chemical concentrations are available from Denal, UC and Bayer, however, this data is not complete (mono-phase in particular) and not always usable because of lack of details on the conditions. For instance a report from Denal (ref. 1) mentions the values below that we interpret as concentration in the liquid phase for a mono-chamber reactor.

vol% at equil (at 80C)										
Start chemical	SiCl4	SiHCI3	SiH2Cl2	SiH3Cl	SiH4					
SiHCl3	11.8	77.1	10.6	0.52	0.04					
SiH2Cl2	0.65	34.7	38.8	15.6	10.2					

Similar data is also available in UC report for the Nasa (ref 11). There is also an article from Bayer AG (ref. 2), that describe concentrations at different heights of a reactive distillator packed with solid catalyst (technological mix between Denal and UC apparatus), but there is no indication on temperatures.



Data from D. Muller et al., Bayer AG (ref. 2)

## 2. HOW TO FIND THE CHEMICAL CONCENTRATIONS?

We can modelize the mono-chamber reactor as a closed (atoms in = atoms out) liquidvapour equilibrium system where HSiCl3 (or H2SiCl2) is allowed to disproportionate and reach a chemical equilibrium. Disproportionation reactions are expected to follows thermodynamic equilibrium thanks to the active catalyst (to be demonstrated in the kinetic study). On the other hand, we assume that decomposition is slow enough for the formation



of pure silicon to be neglected (further discussed in paragraph 10). Hence, by default, we only consider the following chemicals: SiCl4, SiHCl3, SiH2Cl2, SiH3Cl, SiH4, HCl, and H2.

Notations:

•	P pressure (bar),	T,P	
•	T temperature (K)	xi'	gas 🖡
•	N total molar amount of molecules in liquid phase	xi	lia
•	N' total molar amount of molecules in vapour phase		·
•	R gas constant		
For	a chemical i:		
•	xi concentration in liquid phase		
•	xi' concentration in vapour phase		
•	ni molar amount in liquid phase		
•	ni' molar amount in vapour phase		
•	G Gibbs free energy of liquid phase (kJ)		
•	G' Gibss free energy of vapour phase (kJ)		
•	VPi vapour pressure at T (bar)		

- $\mu_i^0$  the molar Gibbs free energy of the pure liquid chemical i (kJ/mol)
- $\mu_i^{0}$  the molar Gibbs free energy of the pure vapour chemical i (kJ/mol)
- $V_i$  molar volume of liquid chemical i, (unit must be chosen so that  $V_i p$  in kJ/mol)

Free energy minimization is not a simple problem as we have to consider both a liquidvapour equilibrium and a reactive equilibrium (with a fairly large number of chemicals). At liquid-vapour equilibrium, the relation between the concentrations in the liquid phase and in the vapour phase is very simple and deduced from Raoult law (this assumes an ideal gas, and an ideal liquid mixture, see ref. 8):

$$\frac{x_i'}{x_i} = \frac{VP_i}{P}$$
[1]

On the other hand, the reactive equilibrium must be found by a numerical minimization (we use the "solver" routine of the excel software, see ref. 3) of the Gibbs free energy, which must be summed in the two phases. If we assume that chemical activities are equal to molar concentrations we have similar relation for the two phases (see ref. 4):

$$G = N \sum_{i} x_{i} [\mu_{i}^{0}(T, P) + RT \ln x_{i}] \qquad [2]$$
$$G' = N' \sum_{i} x_{i} [\mu_{i}^{0}(T, P) + RT \ln x_{i}] \qquad [3]$$

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### 2.1. What is fixed, and what is not?

Such atomically closed system can be described by the following parameters,

- T, P
- N/N' (liquid-vapour ratio of molecules)
- Total (vapour + liquid) amount of each Si, Cl and H atoms

In the usual case, those parameters should be determined (~fixed) before the minimization (which is used to determine each chemical concentrations). However, as will be seen below, the pressure P often can not be fixed and must be determined during/by the minimization.

Neither N or N' are fixed (the number of molecules may change). For this reason, we have to minimize not on the xi (or xi') but on the molar amount ni (or ni'). Hence, we replace variables in equation [2] and [3] following:

$$x_i' = \frac{n_i}{N'}$$
 and  $x_i = \frac{n_i}{N}$  [4]

In order to get rid of half of the variables for the minimization, we assume that the system is at liquid-solid equilibrium during the minimization and hence we use relation [1], which translates into:

$$n_i' = \frac{N'}{NP} n_i V P_i \qquad [5]$$

We must choose initial values such that the system is already at liquid-vapour equilibrium before minimization. For instance, we may start with 100% HSiCl3 and P = vapour pressure of HSiCl3.

#### 2.2. Case with only chlorosilane chemicals

If we consider only SiCl4, HSiCl3, H2SiCl2, H3SiCl, H4Si as chemicals, we have 10 variables (each ni and ni') to determine, and the above would give 10 equations as constraints:

- [5] => 5 equations
- Fixed amount of Si, Cl and H atoms => 3 equations

• Fixed pressure: 
$$P = \frac{\sum n_i V P_i}{\sum n_i} \implies 1$$
 equation

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Fixed N/N':  $\frac{N}{N'} = \frac{\sum n_i}{\sum n_i}$  => 1 equation

The number of equations being equal to the number of variables, no (further) minimization is actually possible unless we free a variable. So, for this case we can either:

- free the values of P and use the minimization to set it (the system is free to set its own equilibrium pressure).
- fix P, but introduce the catalyst as an additional chemical of null vapor pressure and no reactivity. The concentration of the catalyst simply "regulates" the pressure of the system to the initial pressure value.

## 3. MINIMIZATION IN VAPOUR PHASE ONLY

Firstly, we may consider the case where the vapour phase is dominant N' >> N (close to dew point) and hence minimize only G'. This approximation is valid for a solid type catalyst reactor (UC-REC type), where only a small amount of liquid is in contact with the catalyst.

Considering that data for molar Gibbs free energies is only available in vapour phase at 1 bar (actual pressure is several bars) in NIST or JANAF databases, we have to replace as follows in [3] (valid for ideal gas, see ref. 5):

$$\mu_i^{0'}(T, P) = \mu_i^{0'}(T, 1bar) + RT \ln P \quad [6]$$

with [4], this gives:  $G' = \sum_{i} n'_{i} [\mu_{i}^{0}(T, 1bar) + RT \ln(P\frac{n'_{i}}{N'})]$ 

The numerical minimization of G' to find the ni' values is straightforward. Then, xi and xi' values are simply deduced following [4].





## 4. MINIMIZATION IN LIQUID PHASE ONLY

Secondly we may consider the case where the liquid phase is dominant N >> N' (close to boiling point) and hence minimize only G. This approximation is valid for a Denal type reactor if a large amount of liquid remains on the plateau.

Again, considering that the data for molar Gibbs free energies is only available in vapour phase at 1 bar in NIST or JANAF databases, we have to replace in [2] as follows:

- $\mu_i^0(T, P) = \mu_i^0(T, VPi) + v_i(P VPi)$  [7] (valid for incompressible liquid, see ref. 5)
- $\mu_i^0(T, VPi) = \mu_i^0'(T, VPi)$  [8] (liq-vapour equilibrium of the pure chemical i)
- $\mu_i^{0'}(T, VPi) = \mu_i^{0'}(T, P) + RT \ln(VPi/P)$  [9] (valid for ideal gas, see ref. 5)
- and then use relation [6]

with [4], this gives: 
$$G = \sum_{i} n_i \left[ \mu_i^0'(T, lbar) + RT \ln(VP_i \frac{n_i}{N}) \right] + n_i v_i (P - VP_i)$$

The numerical minimization of G to find the ni values is straightforward. Then, xi and xi' values are simply deduced following [4].



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As can be seen from the above, the amount of volatile species in vapour phase (silane in particular) is higher then in the case of paragraph 3. This indicates that it is favorable to have a liquid phase within the reactor.

### 5. MINIMIZATION IN BOTH LIQUID AND VAPOUR PHASES

In the real case, the amount of liquid versus vapour (N/N' ratio) is not well known and it may vary with operation conditions. It is therefore of interest to consider the intermediate situation of an arbitrary N/N' ratio.

In this case, the Gibbs free energy must be minimized on both phase simultaneously by summing G+G'. We can use the expressions of G and G' as estimated in 3. and 4. In order to keep only half of the variables, we replace the ni variables by ni' variable in G using relations [5] (we keep only the vapour variables, although we could keep only the liquid variables as well). This leads to:

$$G + G' = \sum_{i} n_{i}^{\circ} [\mu_{i}^{\circ}'(T, 1bar) + RT \ln(P\frac{n_{i}}{N'})] [1 + \frac{N}{N'} \cdot \frac{P}{VPi}] + n_{i}^{\circ} \frac{N}{N'} v_{i} P(\frac{P}{VPi} - 1)$$

The A term corresponds to the vapour phase only (same as case 2.1). The B term gives the correction for the non-zero N/N'. The C term is a small correction for the liquid volume (may be neglected).



The numerical minimization of G+G' to find the ni' values is straightforward. Then, xi and xi' values are simply deduced following [4].



	SiCI4	SiHCI3	SiH2Cl2	SiH3Cl	SiH4	HCI	H2	Si(s)
% gas	10.71256249	77.28298984	11.7371	0.262891311	0.004417848	1E-97	1E-97	1E-97
% liq	21.52362079	72.64589622	5.77334	0.057049713	9.35308E-05	4.8E-99	2.0028E-100	3.69E-57
Pressure	3.6891486	bars						



	SiCl4	SiHCI3	SiH2Cl2	SiH3CI	SiH4	HCI	H2	Si(s)
% gas	6.6100368	79.99796926	13.1132544	0.27385671	0.004882812	1E-97	1E-97	1E-97
% liq	13.98152079	79.16527144	6.79053426	0.06256467	0.000108828	5.0947E-99	2.1085E-100	3.88378E-57
Pressure	3.883780894	bars						

			100%	HSiCl3 initial,	77C, N/N'=10			
100 90 80 70 60 50 40 30 20 10 0	SiCl4	SiHCl3 SiH20	DI2 SiH3CI	SiH4 I		Si(s)	]%gas  %liq	
	SiCI4	SiHCI3	SiH2Cl2	SiH3CI	SiH4	HCI	H2	Si(s)
% gas	4.793696916	77.96453786	16.4986245	0.70948789	0.033652851	1E-97	1E-97	1E-97
% liq	10.56219409	80.36850458	8.89967672	0.1688433	0.000781317	5.307E-99	2.1963E-100	4.04564E-57
Pressure	4.045644865	bars						

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Note that the minimization is less precise as N/N' increases.

## 6. MINIMIZATION WITH 100% H2SICL2 INITIAL

#### Considering pure liquid phase (N' = 0):



	SiCI4	SiHCI3	SiH2Cl2	SiH3Cl	SiH4	HCI	H2	Si(s)
% gas	0.018316685	7.917941501	44.8432	31.58610746	15.6344009	7.59E-97	1.83357E-95	1E-138
% liq	0.100214815	20.26761074	60.0655	18.66536262	0.901338878	1E-97	1E-97	1E-97
Dreccure	10 0459091	hare				×		

#### Considering pure vapour phase (N = 0):



## 7. MINIMIZATION WITH THE CATALYST

From now, we consider only the pure liquid phase case (N'=0).

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As mentioned earlier, it is possible to run the minimization with a determined pressure if we use the catalyst as a "pressure regulator". Here we have fixed pressure to 2 bars:



Note that the results in the vapour phase are not much different from the result without catalyst (around 4 bar).

### 8. MINIMIZATION WITH LOWER TEMPERATURE

Running the minimization at lower temperature gives lower concentration of disproportionated compounds. From 77C to 25C, H2SiCl2 concentration in liquid phase falls from 9.6% to 7.6%.



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## 9. MINIMIZATION WITH SOME HCL OR H2

Starting with 99% HSiCl3 and 1% HCl, we find a convergence toward H2. Hence, HCl reacts with chlorosilanes to reduce their H content. If we start with H2 1% instead of HCl, we end up with similar values. This corresponds to the experimental case: H2 is found in the output of the disproportionation reactor when adding HCl.

Note that the final amount of chlorosilanes in vapour phase is reduced due to gas volume occupation by H2.



	SiCI4	SiHCI3	SiH2CI2	SiH3CI	SiH4	HCI	H2	Si(s)
% gas	0.846484546	14.04118644	3.04915	0.084444632	0.001290249	3.39E-97	81.97744574	4.5E-139
% liq	10.25672792	79.59738758	9.04506	0.110513953	0.000164735	9.9E-98	0.990149316	9.9E-98
Pressure	22.24815423	bars						



	SiCI4	SiHCI3	SiH2CI2	SiH3Cl	SiH4	HCI	H2	Si(s)
% gas	0.804612671	14.02534983	3.20614	0.090950455	0.001455039	3.39E-97	81.87149227	4.4E-139
% liq	9.761493727	79.60646175	9.52258	0.119176206	0.000186005	9.9E-98	0.99009901	9.9E-98
Pressure	22.27581473	bars						

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#### **10. MINIMIZATION WITH DECOMPOSED CHEMICALS**

The minimization above have been led with the following chemicals: SiCl4, SiHCl3, SiH2Cl2, SiH3Cl, SiH4, HCl, H2. We have excluded other possible chemicals from the minimization, and in particular we have excluded decomposition toward Si. If we allow Si as a chemical, we find a convergence toward Si, H2, HCl and SiCl4. This indicates that from the thermodynamical perspective, the hydrosilanes are not stable. Practically, they are metastable.



	SiCI4	SiHCI3	SiH2CI2	SiH3CI	SiH4	HCI	H2	Si(s)
% gas	1.128300767	4.8108E-99	9E-99	2.08383E-98	2.13598E-97	92.95491	5.916792392	6.11E-41
% liq	25.09839776	5.00656E-98	5E-98	5.00656E-98	5.00656E-98	49.8032	0.131197015	24.9672
Pressure	40.84372088	bars						



## **11. CONCLUSIONS**

We have presented a model to estimate equilibrium concentrations of chloro-silanes, at given temperature, and stoichiometry. From the cases considered we conclude that:

- Disproportionation of HSiCl3 roughly gives 10% of H2SiCl2. However if liquid HSiCl3 is maintained in sufficient amount in reactor, we obtain 17.7% H2SiCl2 in the gas output
- Disproportionation of H2SiCl2 with liquid H2SiCl2 maintained in sufficient amount in reactor, gives 31.6% H3SiCl and 15.6% silane in the gas output.
- It is possible to reduce the pressure by increasing the amount of catalyst, little changing the equilibrium concentrations.
- Disproportionation of HSiCl3 at lower temperature gives a significantly lower amount of H2SiCl2 in output.
- HCl reacts with chlorosilanes to reduce the H content, and produces H2.
- Decomposition to Si is found thermodynamically viable (although it may not be observed). Decomposition of HSiCl3 gives SiCl4, Si, HCl and H2.



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